

## Transaction Information

Tool ID	CMPO-A14
Tool Status	Connected
Location	Woodlands, Singapore
Wafer Size	200 mm
Fab Section	CMP
Tool Available Date	2024-10-09

## General Product Information

Vendor Supplier	EBARA
Model	EPO-222
Vintage	2000
Serial No	PTG00629EX
Asset Description	Ebara 222 Oxide CMP
Software Version	VME3.13.31/TouchPanel3.5.14
CIM	SECS/GEM
Process	Oxide ILD/IMD CMP

## Hardware Configuration (Fab)

System Type	Description	Quantity	Status
Factory Interface	SMIF	2	OK
Others			
Main System	Polishing&CleanerUnit	2	OK
Handler System	Robot1&2 Rorze	2	OK
Options System			

## Hardware Configuration (Subfab / Auxilliary Units)

Description	Quantity	Status
None	0	

## Missing/Faulty Parts / Accesories List

Description	Quantity
Indexer/ SMIFBlowerFan	1

# Tool Pictures

General

PhysicalToolView



General

PhysicalToolView



Hardware Sub-fab	NoAuxiliaryUnit
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# No Auxiliary Equipment

Manufacture Serial

ToolSN



Missing Parts

MissingParts



## Additional Tool Data Files

Ebara 222 Oxide	
System	CMPO-A14
Production	FMFG
Software	
VME (Tool Version)	03.13.31
Touch Panel Version	3.5.14
Endpoint	NA
Hardware	
Polishing Unit	RPC
a) RPC Top Ring Assembly (T1/T2)	Yes/Yes
b) Atomizer Function	Yes
c) Spray bar	# Nozzles
Pusher Unit	Enhanced Nozzles
Dressing Unit	Lightweighth
Turn-Over Unit (Dry & Wet)	In-use
Roll Cleaning Unit	New Stage Clamps
Pencil Cleaning Unit	222 Sponge
Slurry Supply Unit	LineA-CLC
Load/Unload Unit	Inx2200
Robot Unit Rorze	Yes
a) Robot1 (Lower Arm modified with PEEK Material)	Yes
b) Robot2 (Upper/Lower arm modified with PEEK Material)	Yes
Upgrade / CIP Retrofit Items	
DTR Pressure Alarm (Lower Limit/Upper Limit)	Yes
Atomizer Spray Bar	Yes
Roll Unit Stage Clamps	Yes
Roll Unit Stage Belts	Yes
DTR DIW Flow Rate meter	Yes
VME Dual HDD	Yes